

INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)	Docket Number (Optional) TWI-33010	Application Number NEW 10/269,792
	Applicant(s) Kenneth C. Johnson	
	Filing Date Herewith	Group Art Unit Unknown 2812

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>DL</i>	*AA	5,963,329	10/05/99	Conrad et al.	356	372	10/31/97
<i>DL</i>	*AB	6,268,916	07/31/01	Lee et al.	356	369	05/11/99
<i>DL</i>	*AC	6,590,656	07/08/03	Xu et al.	356	369	09/21/01
<i>DL</i>	*AD	5,867,276	02/02/99	McNeil et al.	356	445	03/07/97
<i>DL</i>	*AE	2001/0051856	12/13/01	Niu et al.	702	57	01/17/01
<i>DL</i>	*AF	2002/0038196	03/28/02	Johnson et al.	702	179	08/10/01
<i>DL</i>	*AG	2002/0158193	10/31/02	Sezginer et al.	250	237	02/12/02
<i>DL</i>	*AH	2003/0147086	08/07/03	Rosencwaig et al.	356	601	09/13/02
<i>DL</i>	*AI	2003/0204326	10/30/03	Opsal et al.	702	28	04/02/03
<i>DL</i>	*AJ	2003/0076511	04/24/03	Aikens et al.	356	636	05/14/02

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
<i>DL</i>	AK	WO 03/009063	01/30/03	PCT	G03F	7/20		X
<i>DL</i>	AL	WO 03/054475	07/03/03	PCT	G01B	11/06		X
<i>DL</i>	AM	WO 02/27288	04/04/02	PCT	G01J	3/28		X

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

<i>DL</i>	AN	C.J. Raymond, "Scatterometry for Semiconductor Metrology", Handbook of Silicon Semiconductor Metrology, A. Diebold, Ed., New York 2001, Chapter 18, pp. 477-513 <i>(Ver 2.0)</i>

Examiner <i>Kellie W. Brown</i>	Date Considered <i>8-18-05</i>
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	